



## OPT - S3000

**OPT-S3000** is a single wavelength ellipsometer with variable incident angle and a laser source. The instrument has accurate incident wavelength, wide range of incident angles, and easy sample alignment. It is suitable for enterprise-line detection and control, physics experiments and laboratory applications.

### OPTIONS

- COMBINED OPTICAL PROFILER**
- Micro Spotsize**
- Wafer Mapping**
- Automated Angle of Incidence 20-90°**
- Motorized XY stage**
- Liquid Cell**
- CCD image camera**
- Heater**

**NEW**

### STANDARD FEATURES

- Discrete wavelength ellipsometry
- He-Ne laser or solid state laser
- Excellent accuracy and repetition
- Widest variable angle (20°-90°)
- Non-Destructive Testing
- Easy sample alignment
- Measurement speed is less than 1 sec.
- Large Sample Stage
- User friendly and powerful software and materials library
- Hundreds of materials information in material library.

### TECHNICAL SPECIFICATIONS

Standard wavelength	632.8 nm
Optional wavelength	532 nm, 635 nm, 785 nm, 1064 nm, or 1310 nm
Thickness range of transparent films	0 - 6000 nm
Thickness range of absorptive films	0 - 6000 nm
Accuracy of ellipsometric parameters	$tg(\varphi) \leq 0.01$ , $cos(\Delta) \leq 0.0001$
Accuracy of film thickness measurement	$\pm 0.0001$ nm for SiO <sub>2</sub> standard sample
Stability without compensator	$\pm 0.01^\circ$ in D
Measurement time	less than 1 sec
Sample stage adjustments	Tilt and height
Size of the sample stage	Ø160 mm
Range of angle	20 – 90°
Angle steps	5° ± 0.01